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IAP20 Rec OFCI/PTO 13 FEB 2006 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Izumi FUSEGAWA et al.

Application No.: New U.S. National Stage of PCT/JP2004/011685

Filed: February 13, 2006 Docket No.: 126961

For: METHOD FOR PRODUCING A SINGLE CRYSTAL AND SILICON SINGLE CRYSTAL

WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. Relevance of one or more non-English language reference is discussed in the present specification. See References 5-11.
- 3. One or more reference cited herein was cited in the International Search Report. An English language version of the International Search Report is attached for the Examiner's information. See References 3-5.
- 4. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.
- 5. An English language Abstract of one or more non-English language reference is attached hereto. See References 3-11.
- 6. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([http://www.jpo.go.jp]), and is attached, but has not been reviewed for accuracy. See References 3 & 6-10.

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7. Reference 1 corresponds to Reference 2. Reference 2 corresponds to Reference 4.

Respectfully submitted,

William P. Bertiage

Registration No. 30,024

WPB/nxy

Date: February 13, 2006

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Sheet 1 of 1

Form PTO-1449 (REV. 1/06) INFORMA		US Dept. of Commerce PATENT & TRADEMARK OFFICE ATION DISCLOSURE STATEMENT		ATTY DOCKET NO. 126961 APPLICATION NO. 6 Stage of PCT/JP2004/011685				
(Use several sheets if necessary)				APPLICANTS Izumi FUSEGAWA et al.				
				FILING DATE February 13, 2006				
U.S. PATEN					<u> </u>			
Examiner	Cite	0.	S. I KILN	Docon	ALIVIO			
Initials	No.	Document Number	Date		Name			
	1.	2003/0116082 A1	06/26/2003		Masahiro SAKURADA et al.			
	2.	2002/0157600 A1	10/31/2002		Izumi FUSEGAWA et al.			
		FORE	EIGN PATI	ENT DOC	CUMENTS			
Examiner Initials	Cite No.	Document Number	Da	te	Country	With English Abstract	With English Translation	
	3.	JP-A-2002-201093	07/16/2002		JAPAN	x	x	
	4.	WO 01/63027 A1	08/30/2001		WIPO	x		
	5.	WO 01/81661 A1	11/01/2001		WIPO	х		
	6.	JP-A-09-202684	08/05/1997		JAPAN	х	х	
	7.	JP-A-07-041383	02/10	/1995	JAPAN	х	х	
	8.	JP-A-08-330316	12/13	/1996	JAPAN	х	х	
	9.	JP-A-11-147786	06/02	/1999	JAPAN	х	х	
	10.	JP-A-2000-327485	11/28	/2000	JAPAN	х	х	
			OTHER D	OCUME	NTS			
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	11.	con Dioxide Films Cased by Metal Conta	aminations"; Ulti	a Clean				
	Technology; Vol. 5, No. 5/6; Nippon Steel Corporation; pp. 345-359. (with abstract)							
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EXAMINER					DATE	DATE CONSIDERED		
Examiner:		citation considered, whether or not citati			e with M.P.E.P. 609; draw line through	citation if not in	conformance	

Date: February 13, 2006